

# **A global (volume averaged) model of a chlorine discharge: Dilution with argon and oxygen**

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# Outline

- Chlorine is an electronegative diatomic gas that is widely used in plasma etching of both semiconductors and metals, in particular poly-silicon gate and aluminum interconnects
- Chlorine atoms are believed to be the primary reactant in plasma etching
- The chlorine molecule has
  - a low dissociation energy (2.5 eV)
  - a near-zero threshold energy for dissociative attachment
- All electronic excitations of the molecule appear to be dissociative, and no metastable molecular states are of importance

# *Outline*

- The global (volume averaged) model
  - Model parameters
- Comparison with measurements
- Particle densities
- Sensitivity analysis
- Argon dilution
- Oxygen dilution
- Summary

# The global (volume averaged) model

# *The global (volume averaged) model*

- A steady state global (volume averaged) model was developed for the chlorine discharge using a revised reaction set
- The following species are included
  - electrons
  - the ground state chlorine molecule  $\text{Cl}_2(X^1\Sigma_g^+, v = 0)$ ,
  - the vibrationally excited ground state chlorine molecules  $\text{Cl}_2(X^1\Sigma_g^+, v = 1 - 3)$
  - the ground state chlorine atom  $\text{Cl}(3p^5^2P)$
  - the negative chlorine ion  $\text{Cl}^-$
  - the positive chlorine ions  $\text{Cl}^+$  and  $\text{Cl}_2^+$
- The content of the chamber is assumed to be nearly spatially uniform and the power is deposited uniformly into the plasma bulk

## The global (volume averaged) model

- The particle balance equation for a species  $X$  is given

$$\frac{dn^{(X)}}{dt} = 0 = \sum_i R_{\text{Generation},i}^{(X)} - \sum_i R_{\text{Loss},i}^{(X)}$$

where  $R_{\text{Generation},i}^{(X)}$  and  $R_{\text{Loss},i}^{(X)}$ , respectively, are the reaction rates of the various generation and loss processes of the species  $X$

- The power balance equation, which equates the absorbed power  $P_{\text{abs}}$  to power losses due to elastic and inelastic collisions and losses due to charged particle flow to the walls is given as

$$\frac{1}{V} \left[ P_{\text{abs}} - eVn_e \sum_{\alpha} n^{(\alpha)} \mathcal{E}_c^{(\alpha)} k_{iz}^{(\alpha)} - eu_{B0} n_i A_{\text{eff}} (\mathcal{E}_i + \mathcal{E}_e) \right] = 0$$

## The global (volume averaged) model

- For the edge-to-center positive ion density ratio we use

$$h_L \simeq \left[ \left( \frac{0.86}{(3 + \eta L / 2 \lambda_i)^{1/2}} \frac{1}{1 + \alpha_0} \right)^2 + h_c^2 \right]^{1/2}$$
$$h_R \simeq \left[ \left( \frac{0.8}{(4 + \eta R / \lambda_i)^{1/2}} \frac{1}{1 + \alpha_0} \right)^2 + h_c^2 \right]^{1/2}$$

where  $\alpha_0 \approx (3/2)\alpha$  is the central electronegativity,  
 $\eta = 2T_+ / (T_+ + T_-)$  and

$$h_c \simeq \left[ \gamma_-^{1/2} + \gamma_+^{1/2} [n_*^{1/2} n_+ / n_-^{3/2}] \right]^{-1} \quad \text{and} \quad n_* = \frac{15}{56} \frac{\eta^2}{k_{\text{rec}} \lambda_i} v_i$$

is based on a one-region flat topped electronegative profile

$$\gamma_- = T_e / T_- \quad \text{and} \quad \gamma_+ = T_e / T_+$$

## The global (volume averaged) model

- The diffusional losses of the neutral chlorine atoms to the reactor walls are given by

$$k_{\text{Cl,wall}} = \left[ \frac{\Lambda_{\text{Cl}}^2}{D_{\text{Cl}}} + \frac{2V(2 - \gamma_{\text{rec}})}{Av_{\text{Cl}}\gamma_{\text{rec}}} \right]^{-1} \text{ s}^{-1}$$

- $D_{\text{Cl}}$  is the diffusion coefficient for neutral chlorine atoms
- $v_{\text{Cl}} = (8eT_g/\pi m_{\text{Cl}})^{1/2}$  is the mean Cl velocity
- $\gamma_{\text{rec}}$  is the wall recombination coefficient for neutral chlorine atoms on the wall surface
- $\Lambda_{\text{Cl}}$  is the effective diffusion length of neutral chlorine atoms

$$\Lambda_{\text{Cl}} = \left[ \left( \frac{\pi}{L} \right)^2 + \left( \frac{2.405}{R} \right)^2 \right]^{-1/2}$$

- The wall recombination coefficient  $\gamma_{\text{rec}}$  is one of the most important parameters in chlorine discharge modelling

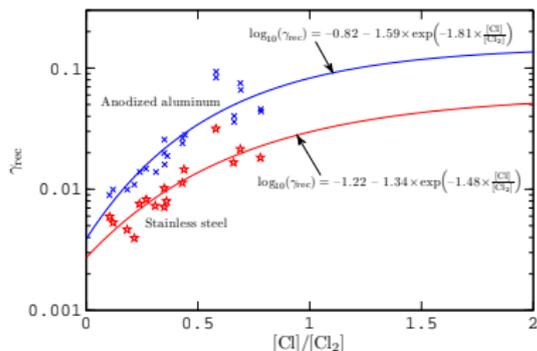
# Model parameters

# Surface recombination

- The wall recombination probability,  $\gamma_{\text{rec}}$ , is a very important quantity in all low pressure molecular discharges
- We use the wall recombination coefficient measured by Stafford et al. (2009) for stainless steel

Guha et al. J. Appl. Phys., **103** 013306 (2008)

Stafford et al. J. Phys. D: Appl. Phys. **42** 055206 (2009)



A fit to the measured data is for anodized aluminum

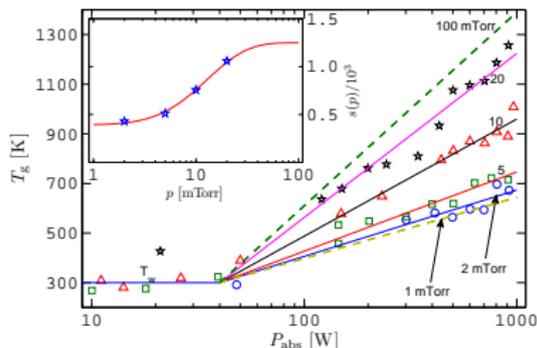
$$\log_{10}(\gamma_{\text{rec}}) = -0.82 - 1.59 \exp\left(-1.81 \times \frac{[\text{Cl}]}{[\text{Cl}_2]}\right)$$

and for stainless steel

$$\log_{10}(\gamma_{\text{rec}}) = -1.22 - 1.34 \exp\left(-1.48 \times \frac{[\text{Cl}]}{[\text{Cl}_2]}\right)$$

# Gas temperature

- Donnelly and Malyshev (2000) found that the neutral chlorine gas temperature was between 300 and 1250 K, increasing with power and pressure up to 1000 W and 20 mTorr



A fit through the measured data gives

$$T_g(P_{\text{abs}}, p) = 300 + s(p) \frac{\log_{10}(P_{\text{abs}}/40)}{\log_{10}(40)}$$

where

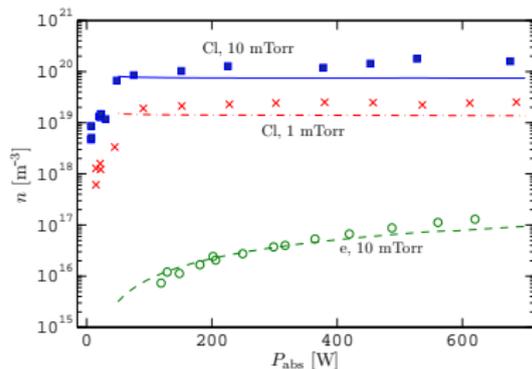
$$s(p) = 1250 (1 - e^{-0.091 \times p}) + 400 e^{-0.337 \times p}$$

Donnelly and Malyshev, Appl. Phys. Lett. **77** 2467 (2000)

# Comparison with experiments

# Comparison with experiments

- Densities of neutral Cl atoms and electrons versus power
- The agreement with the measured electron density is excellent
- The calculated density of atomic chlorine is in a very good agreement with the measured data at both 1 and 10 mTorr



- inductively coupled cylindrical stainless steel chamber
- $L = 20$  cm and  $R = 18.5$  cm

Malyshev and Donnelly, J. Appl. Phys. **88** 6207 (2000)

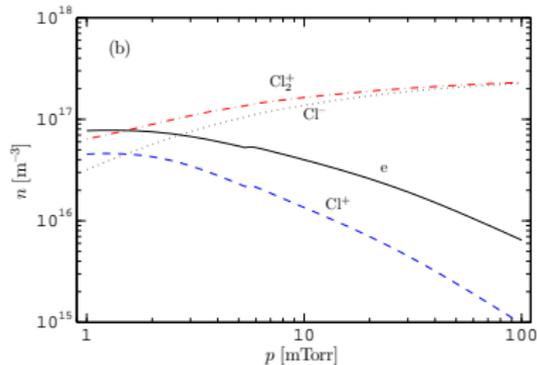
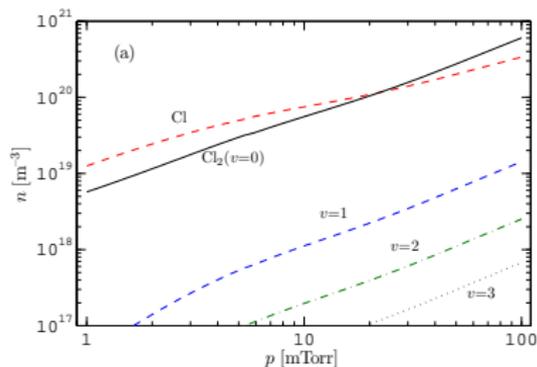
Malyshev and Donnelly, J. Appl. Phys. **90** 1130 (2001)

# Particle densities

# Particle densities

- Atomic chlorine Cl is the dominant particle at low pressure, but the chlorine molecule  $\text{Cl}_2$  has a larger density above 20 mTorr
- The density of the atomic ion  $\text{Cl}^+$  is always much smaller than the  $\text{Cl}_2^+$  density, decreasing with pressure
- a cylindrical stainless steel chamber  
radius  $R = 18.5$  cm  
length  $L = 20$  cm

$$P_{\text{abs}} = 323 \text{ W}$$



# Sensitivity analysis

## *Sensitivity analysis – EEDF*

- The discharge pressure was 10 mTorr and the absorbed power 323 W
- We allow the electron energy distribution function to vary according to the general distribution function

$$f(\mathcal{E}) = c_1 \mathcal{E}^{1/2} \exp(-c_2 \mathcal{E}^x)$$

where the coefficients  $c_1$  and  $c_2$  depend on the energy  $\mathcal{E}$  and the distribution parameter  $x$

	$[\text{Cl}]/n_g$	$[\text{Cl}^+]/n_+$	$\alpha$	$T_e$	$n_e$
$x: 1 - 2$	↓ 1.01	↓ 1.40	↑ 1.34	↑ 1.43	↓ 1.65

## *Sensitivity analysis* – $\gamma_{\text{rec}}$

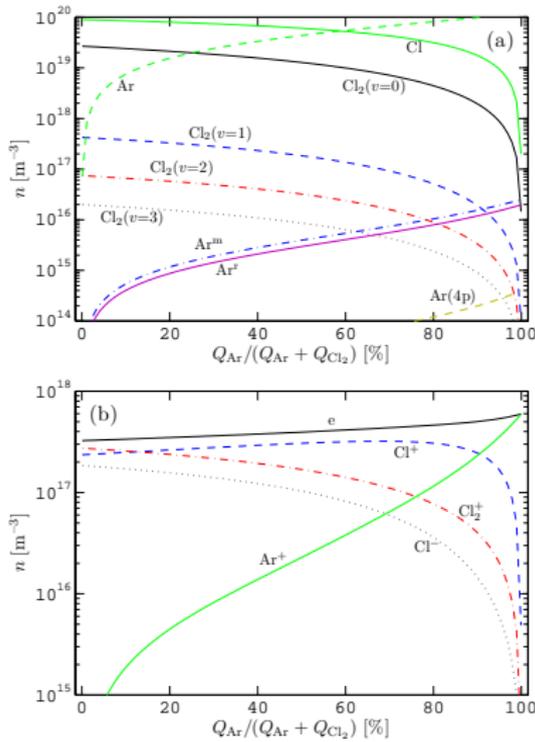
	$[\text{Cl}]/n_{\text{g}}$	$[\text{Cl}^+]/n_{+}$	$\alpha$	$T_{\text{e}}$	$n_{\text{e}}$
$\gamma_{\text{rec}}: 10^{-4} - 1$	↓ 5.75	↓ 34.6	↑ 4.25	↑ 1.13	↓ 1.59

- The wall recombination coefficient  $\gamma_{\text{rec}}$  determines the rate coefficient for recombination of neutrals on the wall
- However, varying  $\gamma_{\text{rec}}$  has a much larger effect on the atomic ion fraction than on the dissociation fraction

# Argon dilution

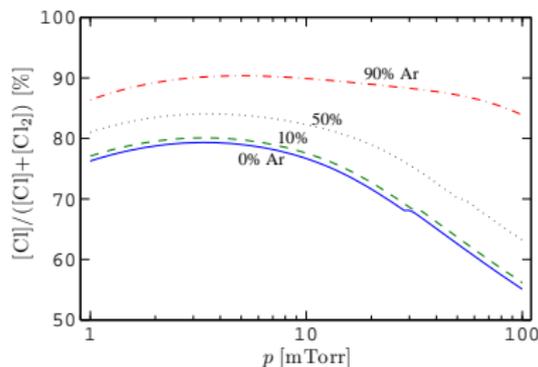
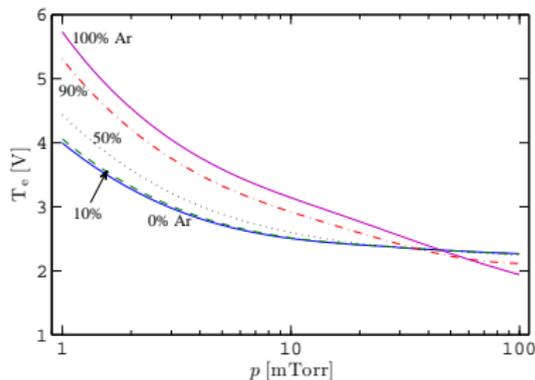
# Argon dilution – particle densities

- The discharge is highly dissociated with Cl atoms being the dominant neutral until the argon content is 60%
- The  $\text{Cl}^+$  density increases until the argon dilution is 68%
- This is likely a result of the increased electron temperature
- A cylindrical stainless steel chamber  $L = 10$  cm and  $R = 10$  cm  
Pressure is  $p = 10$  mTorr  
Power  $P_{\text{abs}} = 500$  W  
 $Q_{\text{Cl}_2} + Q_{\text{Ar}} = 100$  sccm



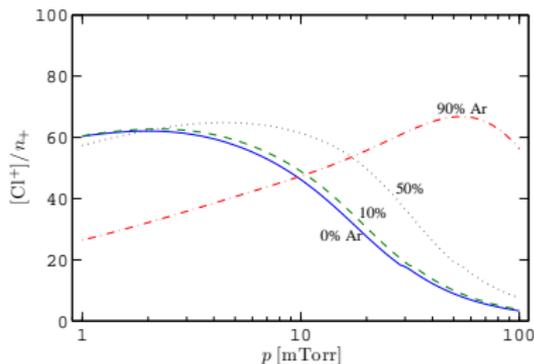
# Particle densities

- The electron temperature increases with argon content at low and intermediate pressures
- The chlorine dissociation increases with argon content
- The chlorine dissociation fraction decreases with increased pressure above 10 mTorr at low and moderate argon contents



# Particle densities

- The pressure dependence of the fraction of  $\text{Cl}^+$  positive ions can be modified by argon dilution
- It peaks at low pressure when the argon content is low or moderate, but at high pressure in an argon dominated discharge
- The peak value increases slightly with increased argon content, even when the argon content has reached 90%



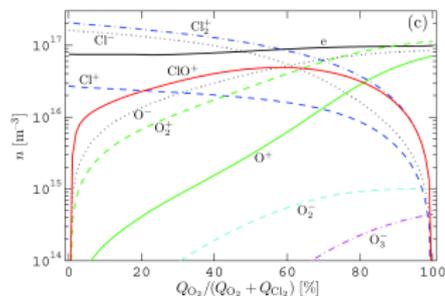
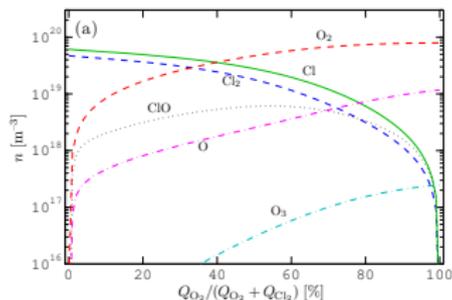
Thorsteinsson and Gudmundsson,

*J. Phys. D.*, **43** 115201 (2010)

# Oxygen dilution

# Particle densities

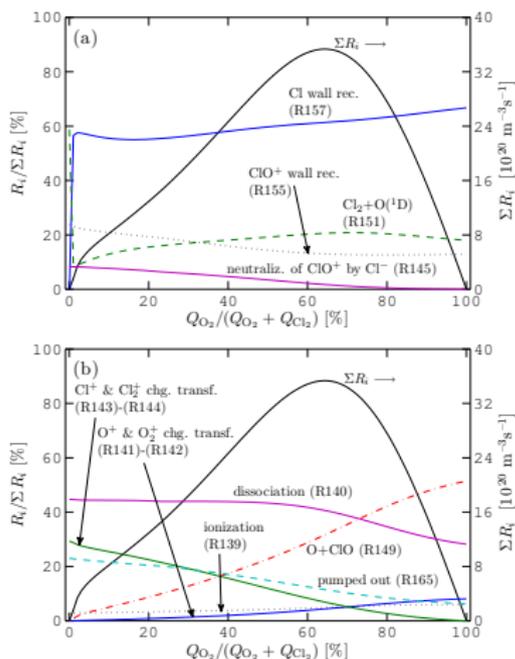
- The  $\text{Cl}^+$  density decreases with increased oxygen dilution
- The chlorine-oxide molecule  $\text{ClO}$  and its ion  $\text{ClO}^+$  peak when  $\text{Cl}_2$  and  $\text{O}_2$  flowrates are roughly equal
- The  $\text{O}_2(a^1\Delta_g)$  density is about 9 – 10 % of the total  $\text{O}_2$  density
- The electron density increases about 30 % between pure chlorine and pure oxygen discharge



A cylindrical stainless steel chamber  
 $L = 10$  cm and  $R = 10$  cm  
 $p = 10$  mTorr and  $P_{\text{abs}} = 500$  W

# Particle densities

- The total rate for creation and loss of ClO molecules is at maximum when the oxygen content is 65%.
- Wall recombination of Cl molecules, is the dominating pathway for creation of ClO molecules
- The bulk processes and recombination of ClO<sup>+</sup> ions at the wall account for roughly 33–43% of the total rate for ClO creation, combined



# Summary

# Summary

- A global model of  $\text{Cl}_2$ ,  $\text{Cl}_2/\text{Ar}$  and  $\text{Cl}_2/\text{O}_2$  discharges has been developed
- The chlorine discharge remains highly dissociated in all conditions, being over 20 % at the lowest power and highest pressure explored
- $\text{Cl}^-$  ions are essentially entirely produced in dissociative attachment of electrons to  $\text{Cl}_2$  and lost to mutual neutralization with  $\text{Cl}^+$  and  $\text{Cl}_2^+$
- The effect of vibrationally excited chlorine molecules  $\text{Cl}_2(v > 0)$  is not great, at most increasing the  $\text{Cl}^-$  production by about 14 %
- The  $\text{Cl}^+$  density increases with increased argon dilution but decreases with increased oxygen dilution
- The  $\text{ClO}$  molecule is mainly created by recombination at the discharge wall

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Download the slides at

<http://www.raunvis.hi.is/~tumi/plasma.html>

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